



Inventor: Kie Y. Ahn et al.

Title: A Dielectric Layer Forming Method and Devices Formed Therewith

Assignee: Micron Technology, Inc.

Docket No. MI22-1534

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MR
APR 11/03
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TC 2800 MAIL ROOM

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56.

Copies of documents listed on the Form PTO-1449 are enclosed.

No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 31 Mar 2003

Attorney: J. E. Lake
James E. Lake
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